



THE UNIVERSITY *of*  
NEW MEXICO

# Overview of Schunk\* Research Group Activities

**Department of Chemical and Biological  
Engineering**

**University of New Mexico**

**March 2019**

**Research Assistant Professor:** Kristianto Tjiptowidjojo

**Graduate Students:** Andrew Cochran (Ph.D), Robert Malahkov (Ph.D)

**Staff:** Weston Ortiz

**Postdocs:** hiring one or two more in the next several weeks.

**Collaborators (faculty):** Steve Brueck (CHTM), Roger Bonnecaze, Sang Han (UNM)

**Collaborators (industry/national laboratories):** NREL, ORNL, LBNL, SLAC, 3M, P&G, Corning, Avery Dennison, Ballard Inc.

\*Sandia National Laboratories is a multimission laboratory managed and operated by National Technology & Engineering Solutions of Sandia, LLC, a wholly owned subsidiary of Honeywell International Inc., for the U.S. Department of Energy's National Nuclear Security Administration under contract DE-NA0003525

# Schunk Research Group Sponsors

Two Areas of Active Research – Nanomanufacturing and Complex Fluids

- NSF – NASCENT ERC (NASCENT-erc.org) (\$130K/year)
  - NASCENT = Nanomanufacturing Systems for mobile Computing and Energy Technologies
- NSF – SNM project (thin-absorber PV) – Sang Han (PI) - \$50K/year
- UNM – Matching funds for NSF ERC (\$30K/year)
- Procter and Gamble (Unrestricted grants \$40K and in the past \$50K))
- 3M Corporation (Unrestricted grant \$50K)
- Gillette (Unrestricted grant \$50K)
- Sandia National Laboratories (Project funds - \$200K+ consistently since 2014)

# Schunk Research Group Competencies and Strengths

- Modeling and simulation: from code development to application.
  - Algorithm development (Finite element technology in continuum mechanics)
  - Algorithm development (Discrete element modeling technology – colloids)
  - High-performance computing (MPI-based parallel processing)
  - Matrix solver technology, preconditioner development
  - Thin-shell mechanics
- Multiphase flow (poro-elastic media, particulate flows)
- Chemically reacting systems (electrochemistry for battery performance modeling)
- Viscoelastic flow (Constitutive equation development, solver development)
- Free and moving boundary problems
- Fluid-structure interactions
- Heterogeneous materials (predictive properties)
- Manufacturing (printing thin-film coating, casting, welding/soldering/brazing, wet etching/microelectronics processing ...)

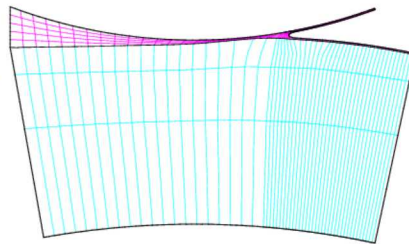
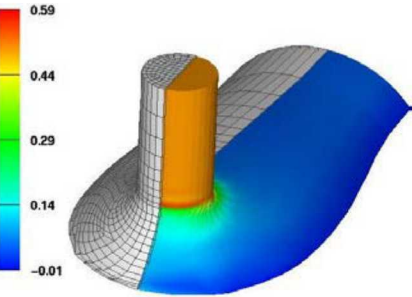
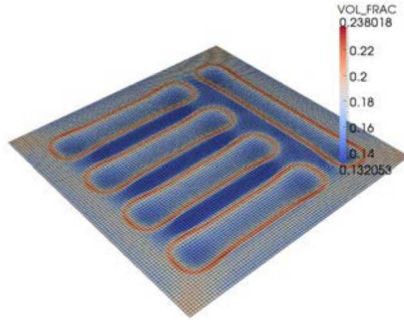
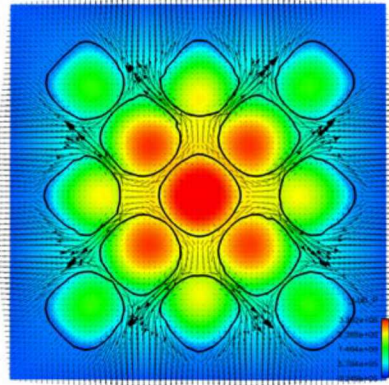


# Research Group Capability: Goma 6.0



**2014 R&D 100 Award Winner**

- Multiphysics *finite element* code, suitable for both *research* and *production*
- Fully-coupled *free* and moving *boundary* parameterization – ALE, Level Set, etc.
- Modular code; *easy to add equations* – currently has 170+ differential equations
- *Open source*! Available at <http://goma.github.io>
- *Goma 6.0. training* is available on regular basis



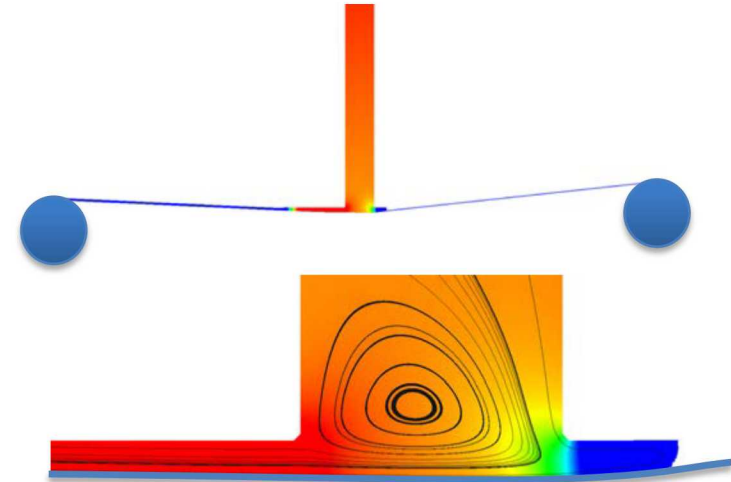
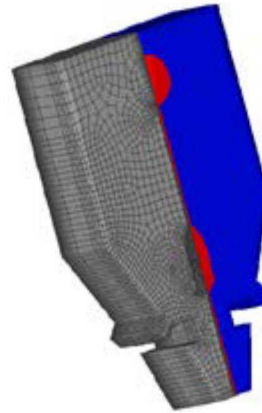
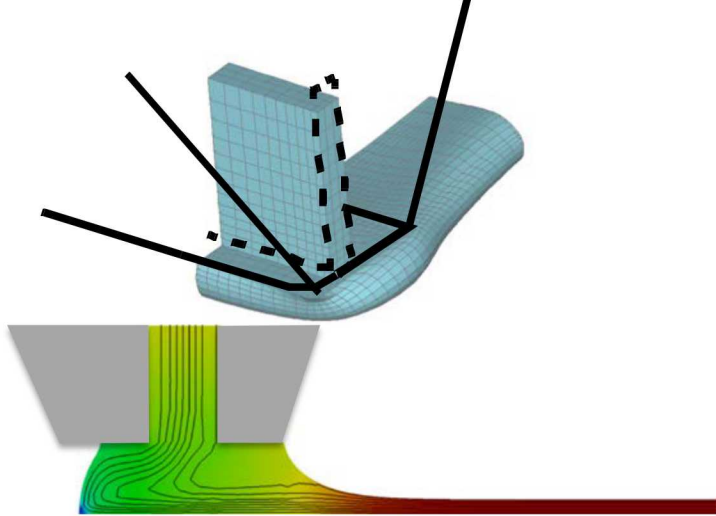
***Goma has been used successfully in coating manufacturing for 2 decades!***

*...Also a competency in LAMMPS for colloidal rheology and self/directed assembly*

# Schunk Research Group Modeling Capabilities

Slot Die Coating

Thin-Film Coating Tensioned Web over Slot Die Coating

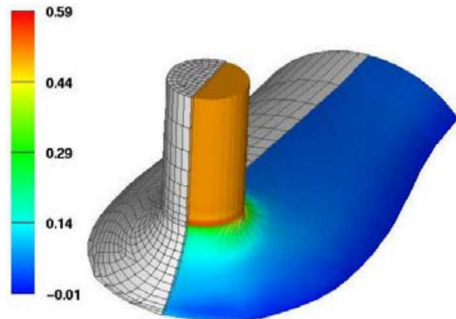


Free Surface Tracking/Capturing

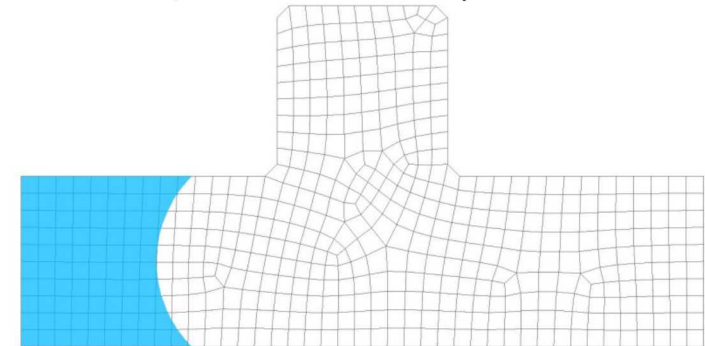
Arbitrary Lagrangian Eulerian (ALE)

Eulerian

Deform mesh to track free surface



Fixed mesh, use level set to capture free surface



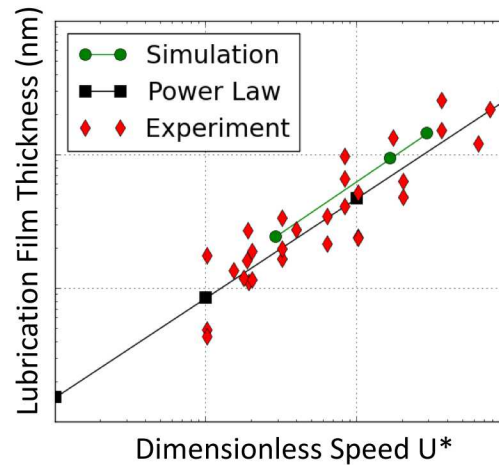
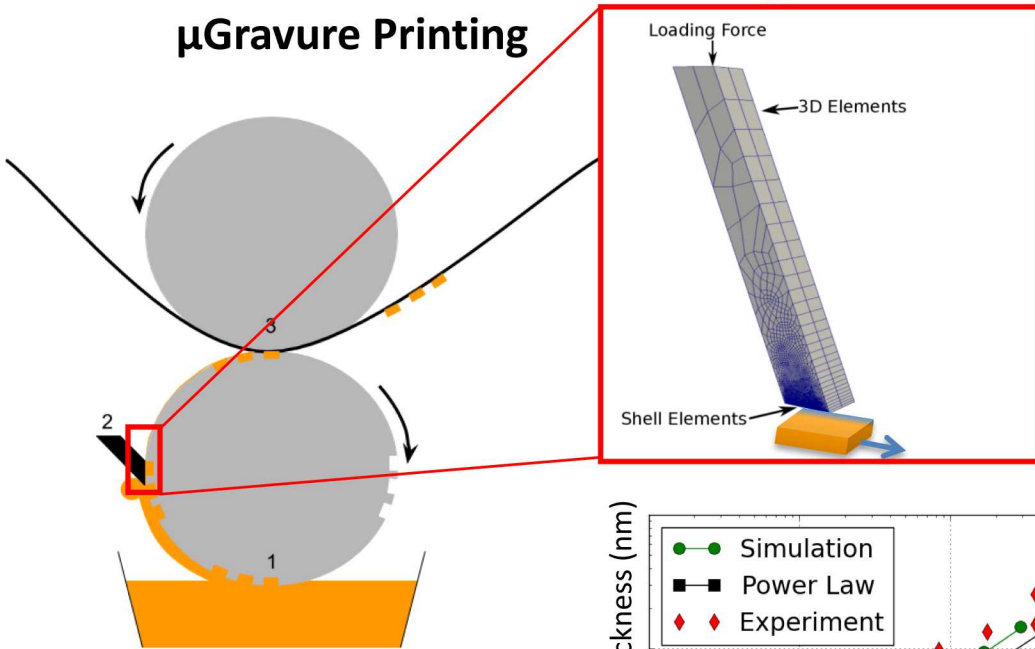
- Full 3-D simulation of continuous liquid film coating with finite element method
- Capable of handling free surfaces two ways: ALE and level set method



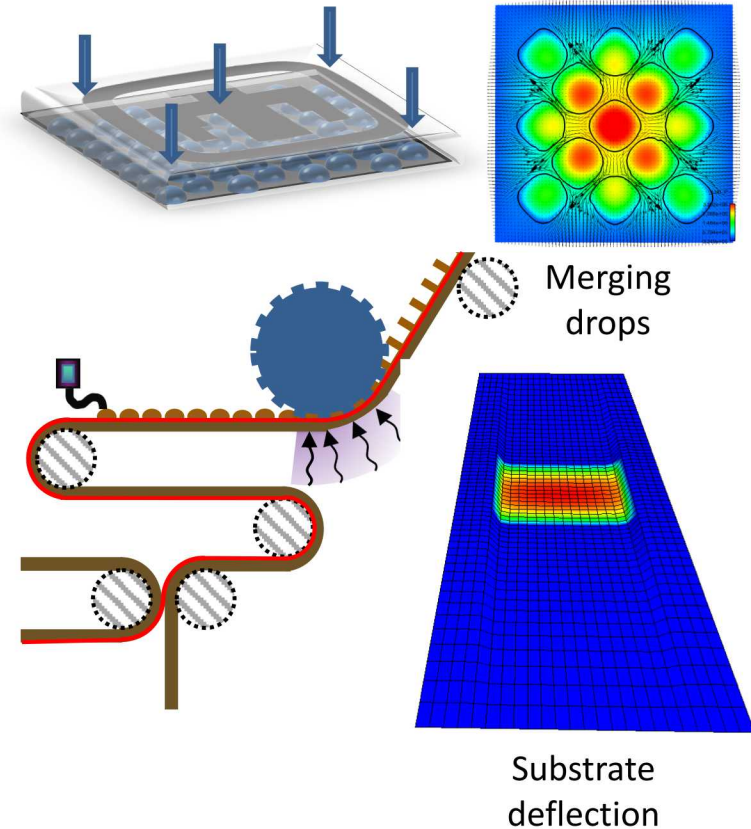
# Schunk Research Group Modeling Capabilities

## Printing and Nanopatterning

**$\mu$ Gravure Printing**



**Nanoimprint Lithography**



- *Prediction of residual film thickness is validated with experiments*
- *Capable of modeling fluid structural interaction (FSI) of nanopatterning process at manufacturing scale*

# NASCENT Overview



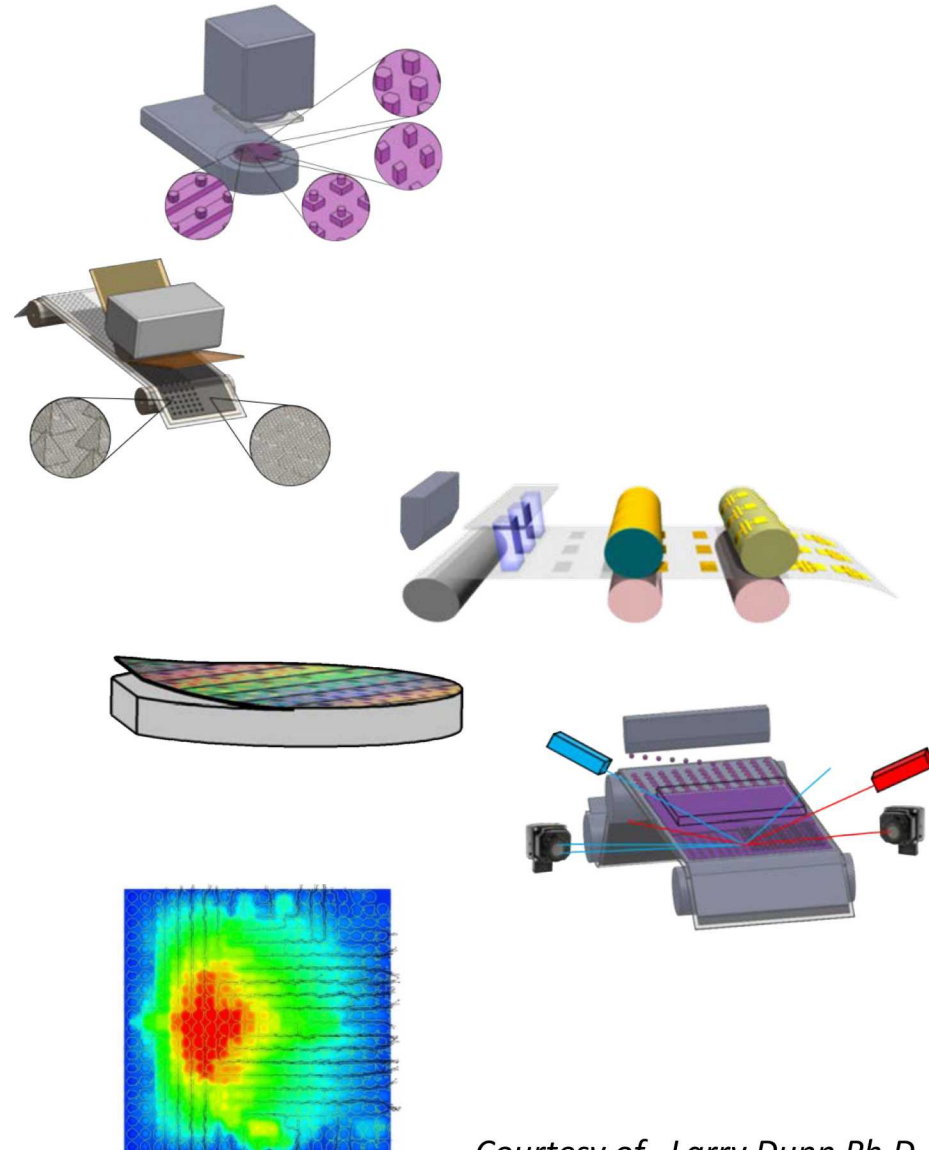
- **University research center** funded in September 2012, 10 years of expected funding from the National Science Foundation (NSF).
- NASCENT has an annual budget of >\$4 million, and a **team of more than 75** graduate students, post-doctoral researchers, and faculty members.
- NASCENT Mission: To create **high throughput**, reliable and versatile **nanomanufacturing systems** and processes that will revolutionize future generations of mobile computing and energy devices.
- We are a **Nanomanufacturing R&D Center**

*Courtesy of Larry Dunn Ph.D.*

***For more information, see Larry Dunn Ph.D. at the NASCENT booth***

# NASCENT Enabling Technologies

- 2D/3D Nanosculpting
  - Wafer Scale and R2R Substrates
- Roll-to-roll (R2R) graphene transfer
- R2R Printable Nanomaterials
- Exfoliated crystalline materials
- In-line nanometrology
- Scale-Up and Reduced Order Model Simulators

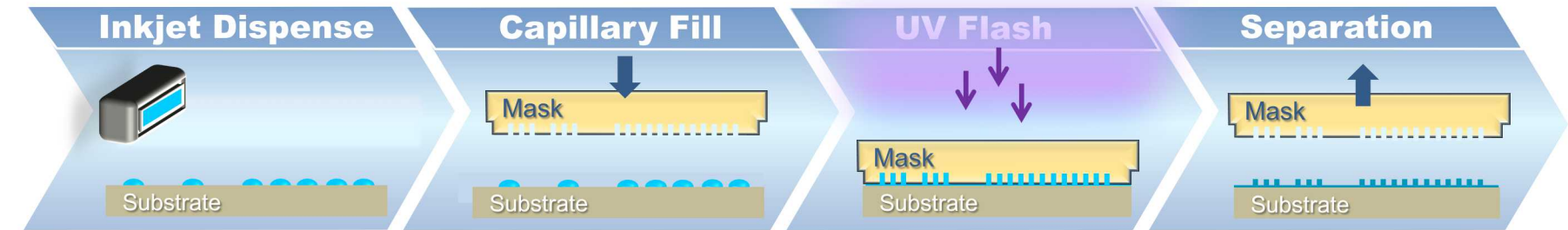


*Courtesy of Larry Dunn Ph.D.*



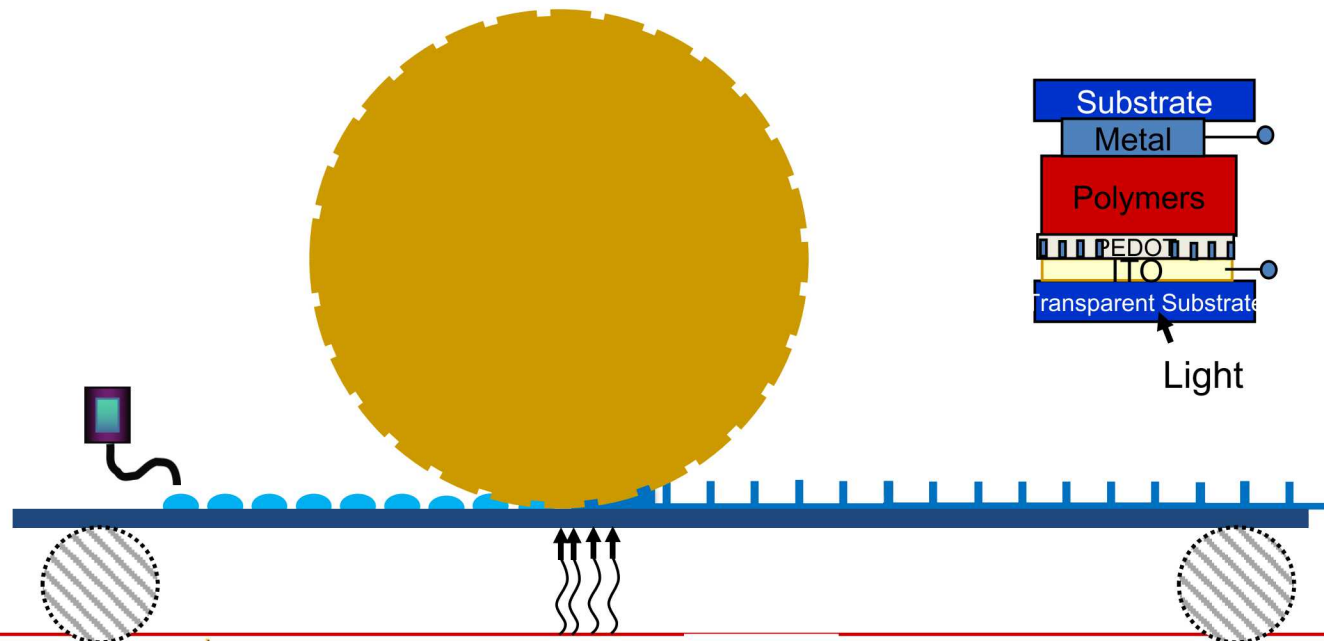
# Nanosculpting: Nanoimprint Lithography

## Jet Flash Imprint Lithography™ (J-FIL™)



Courtesy of  Molecular Imprints

## Roll-to-Roll Nanoimprint Lithography (R2R\_NIL)



High density storage



Courtesy of Akhilesh Jain

# Nanoimprint Lithography

## Project Goal

### Optimize Rate & Yield

- Minimize Gas Trapping
- Obtain Uniform Residual Layer

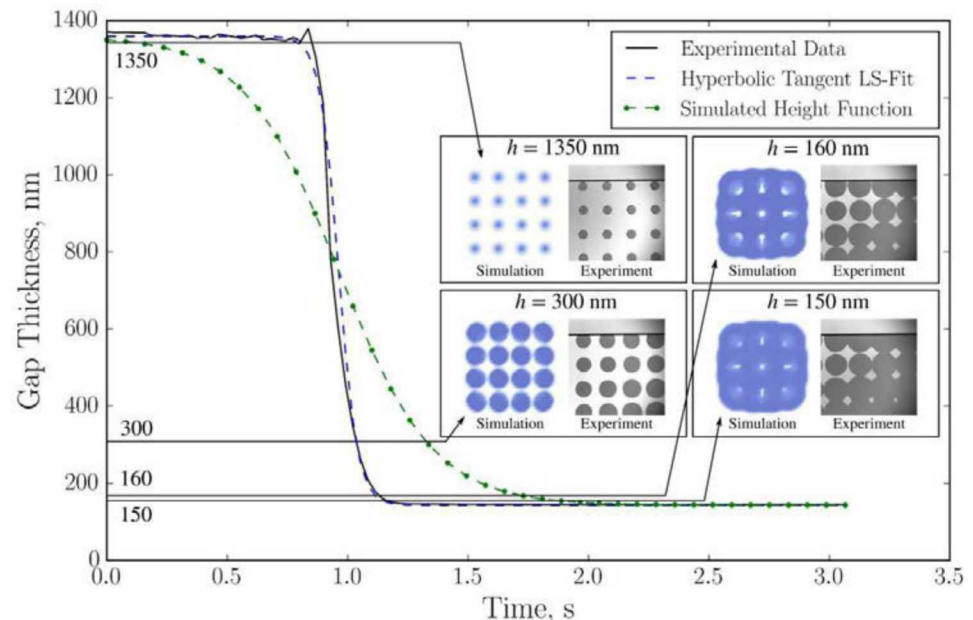
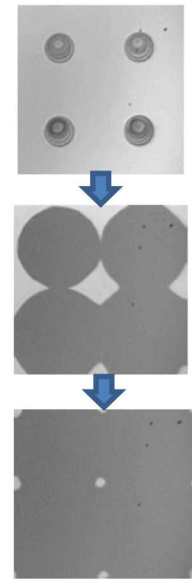
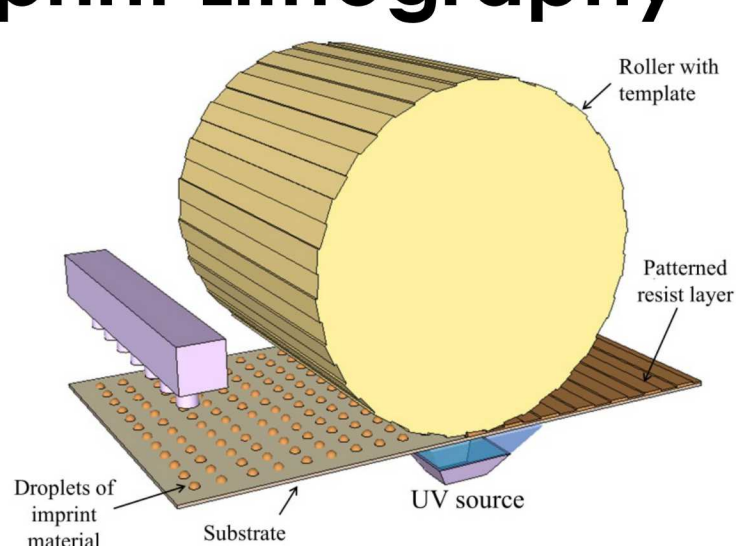
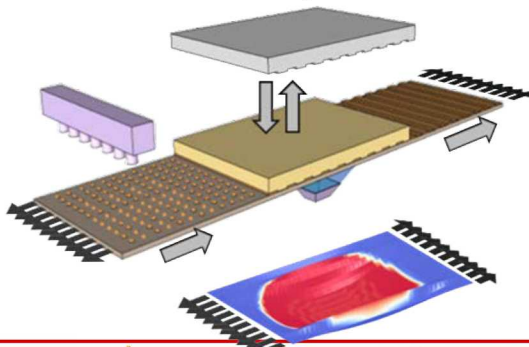
## Approach

### Develop a Multiphase Flow Model

- Not tracking liquid-gas interfaces
- Incorporate gas compression and dissolution

## Updates

- Completed multiphase flow model
- Incorporating structure mechanics of substrates and or templates



Comparison of the model prediction with experiment

# Slot-Die Coating

## Project Goal

### Use slot die for nanomanufacturing

- Scale-up: Ultrathin coatings ( $<1\mu\text{m}$  wet thickness)
- Small-lot patch coatings

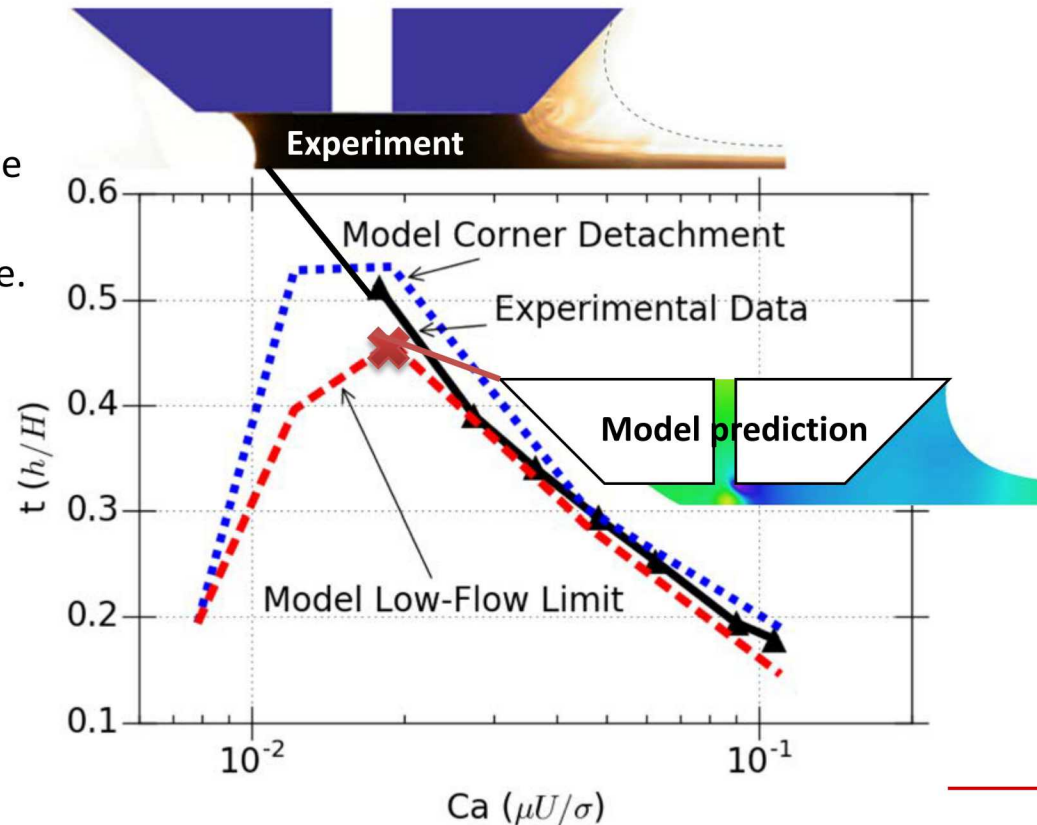
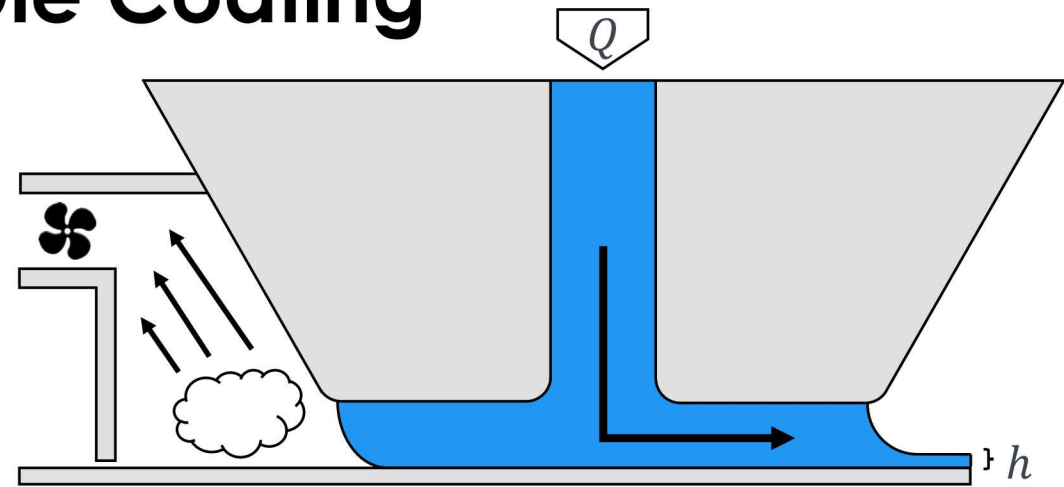
## Approach

### Develop slot coating flow model

- Steady 2-D Navier-Stokes with Arbitrary Lagrangian Eulerian (ALE) method to track free surface
- Predict minimum film thickness achievable, i.e. low flow limit

## Updates

- Validated the model
- Uncovered mechanisms of low-flow limit





# Gravure Printing

## Project Goal

### Deposit functional 0D and 1D nanomaterials

- Use gravure printer – high speed, R2R method
- Push printing resolution  $<1\text{ }\mu\text{m}$

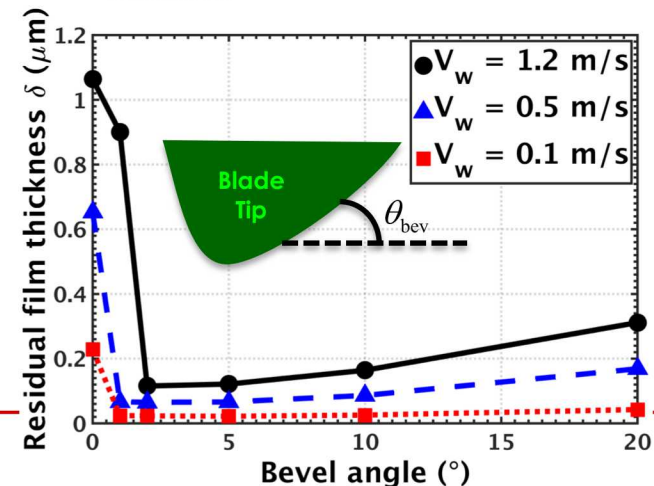
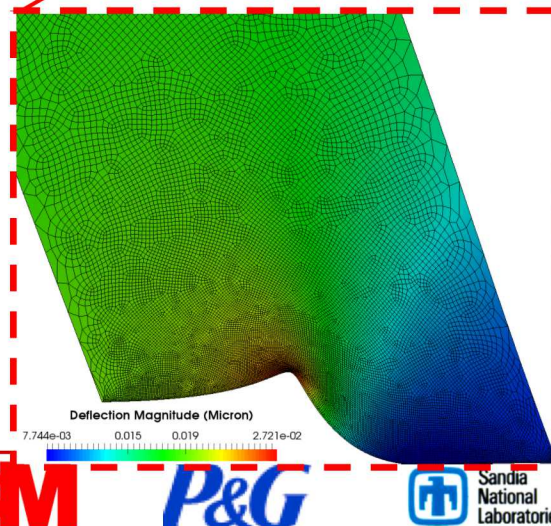
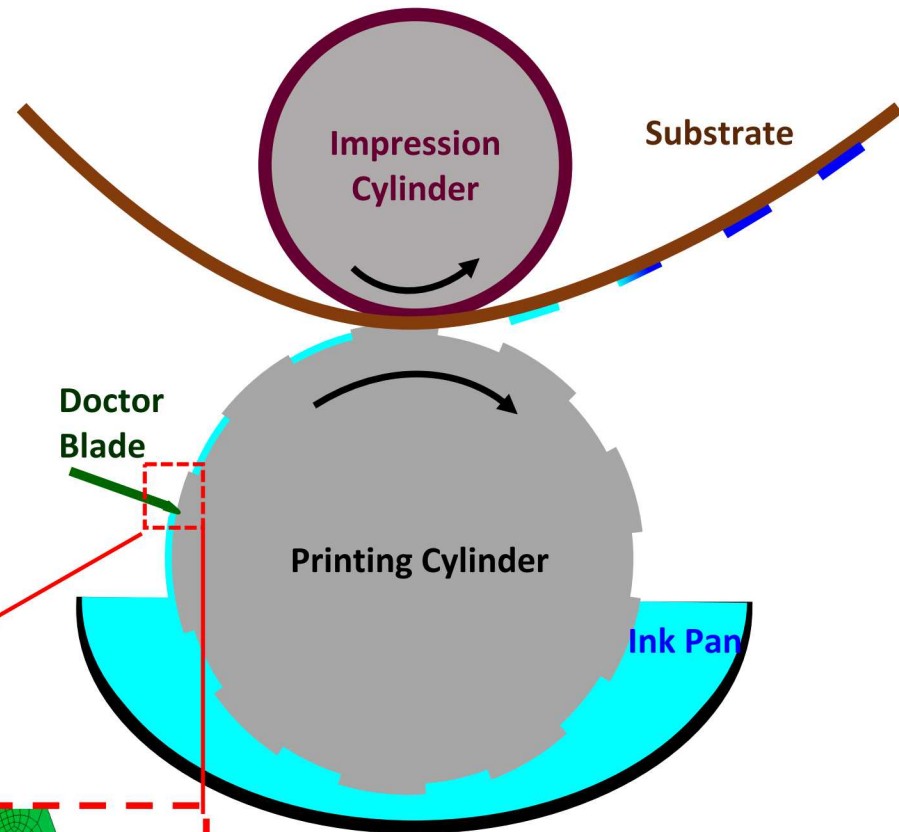
## Approach

### Develop gravure printer model – doctoring step

- Coupling between 3-D elasticity equation and 2-D lubrication flow
- Predict residual film thickness

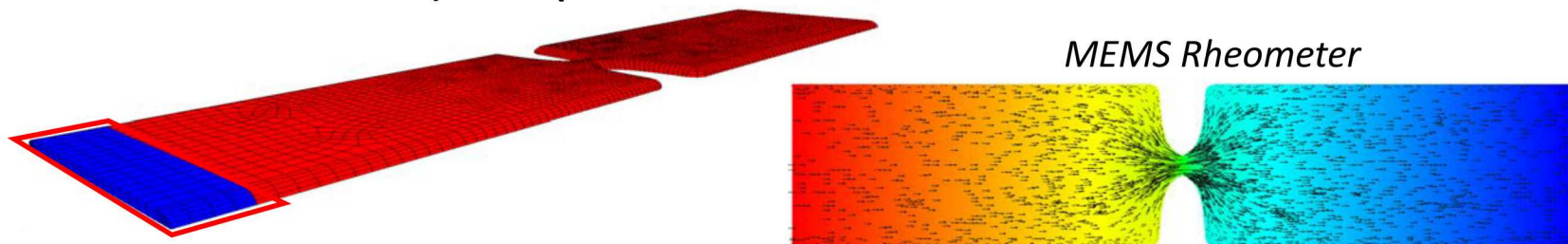
## Updates

- Validated the model
- Optimized blade shapes

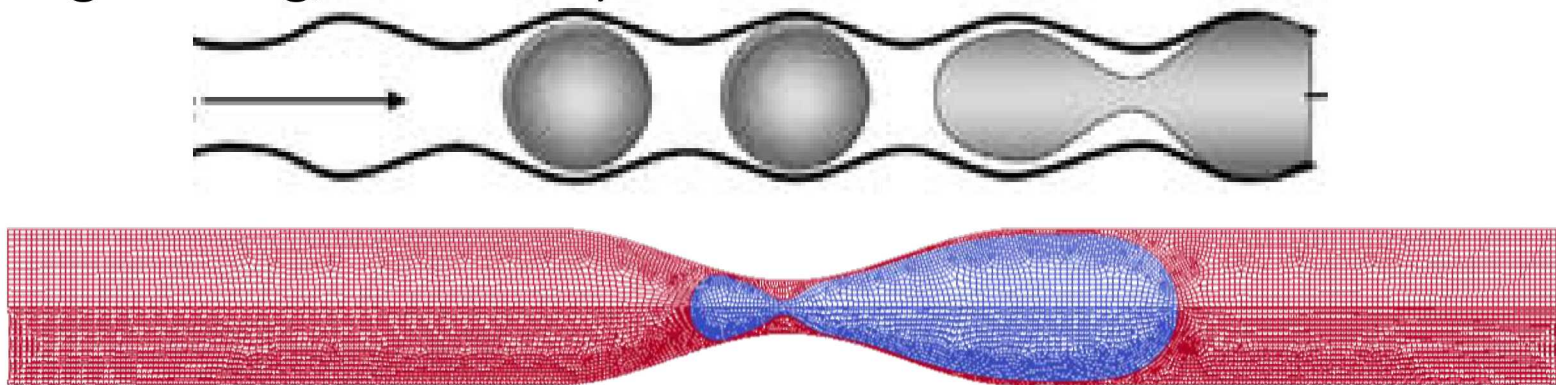


# Research in Computational Viscoelasticity

Complex Fluids (e.g. yield-stress fluids and worm-like micelle solutions) -- Sponsors P&G/Gillette



Viscoelastic flow application in enhanced oil recovery (assisting Prof. Matt Balhoff, Department of Petroleum Engineering, UT Austin)



Sponsor P&G, Gillette, SNL. Collaborator: UT Austin



# Roll-to-Roll Advanced Materials Manufacturing Lab Collaboration

Collaboration Lead: Claus Daniel (ORNL)  
Email: [danielc@ornl.gov](mailto:danielc@ornl.gov); Phone: 865-946-1544

Argonne National Laboratory Lead: Gregory Krumdick  
Lawrence Berkeley National Laboratory Lead: Vince Battaglia  
National Renewable Energy Laboratory Lead: Michael Ulsh  
Sandia National Laboratory Lead: Randy Schunk  
Oak Ridge National Laboratory Lead: David Wood

**Presenters: Claus Daniel and Scott Mauger**  
**2019 Hydrogen and Fuel Cells Program**  
**Annual Merit Review**  
**May 1, 2019**

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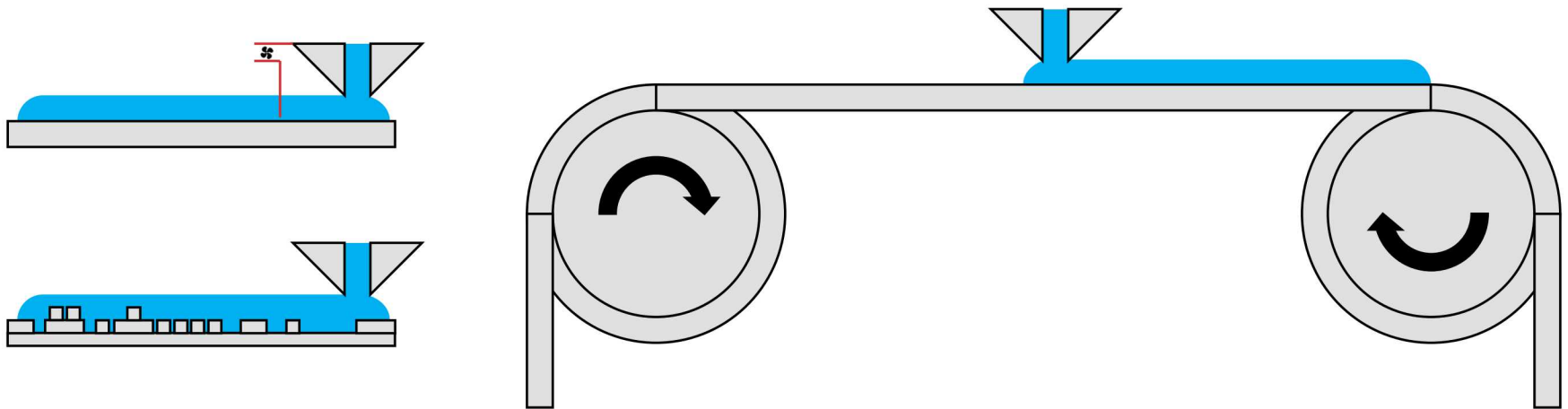
**OAK RIDGE**  
National Laboratory



**R2R**

This presentation does not contain  
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otherwise restricted information.





# Slot Die Coating Model

Robert Malakhov<sup>†</sup>, Kristianto Tjiptowidjojo<sup>‡</sup>, P.  
Randall Schunk<sup>‡§</sup>



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# Overview

## Timeline and Budget

- Project Start Date: 10/01/2016
- Project End Date: 9/30/2018
- FY18 AMO Funding: \$4M
- FY18 FCTO: \$0 of FCTO
- FY19 planned: \$150K of FCTO for new CRADA with Proton On-Site
- \$850K of FCTO contribution in negotiation

## Technology Barrier

- Develop roll to roll manufacturing techniques to reduce the cost of automotive fuel cell stacks at high volume (500,000 units/year) from the 2008 value of \$38/kW to \$20/kW by 2025.
- Lack of high-volume MEA processes
- Project partners:
  - ORNL, NREL, ANL, LBNL, SNL
  - Proton On-Site
  - Eastman Business Park



# Summary

## Relevance:

- R2R is the only manufacturing process platform that will meet cost and volume targets for PEM MEAs
- Cost reduction need: 60 cents/mile in 2013 to 13 cents/mile in 2025

## Approach:

- Leverage unique capabilities, facilities, expertise across the four labs
- Focus on MEA structure of industrial interest (GDEs)
- Achieve reduction in process steps and energy consumption

## Collaborations:

- ORNL, ANL, LBNL, NREL, Eastman Business Park, industry

## Accomplishments:

- Determined function of ionomer overlayer in spray-coated GDEs
- Characterized influence of MPL roughness on GDE performance and properties
- Developed materials and process for single-process R2R GDEs with performance better than spray-coated CCMs or GDEs – **ACHIEVED PROJECT GOAL**



# Multilayer Slot/Slide Coating Process Models

## Achievement

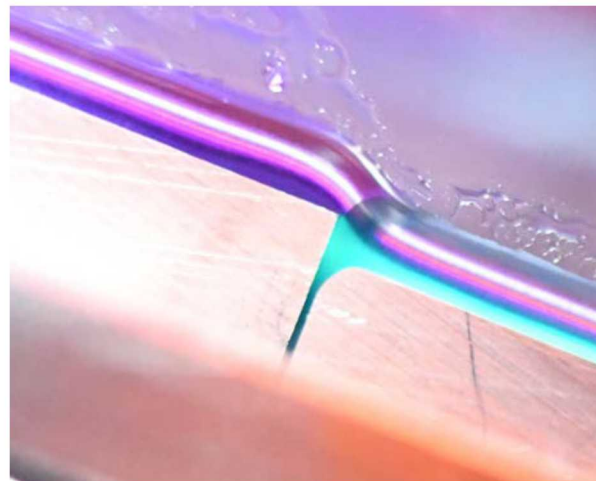
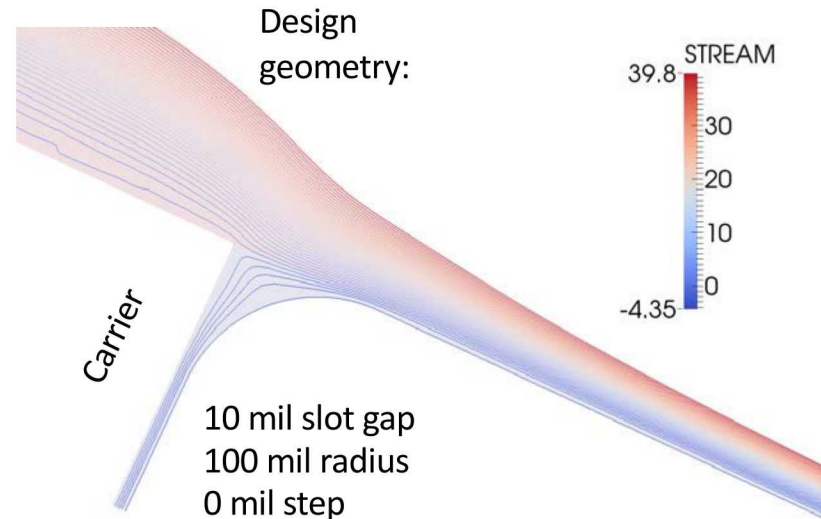
Completed workflows and demonstrated multilayer slot and slide coating process models using Goma 6.0.

## Significance and impact

- Process models of pre-metered coating flow deposition capillary hydrodynamics have proven track record of accelerated process development
- Models of consortium's slot- and slide-deposition systems with accommodation for 3+ simultaneous miscible layers has no precedence (multiple layers of varying rheology)
- Modeling and simulation of the coating process, once validated, will enable process operating windows with key parameters (layer flow rates, webspeed, slide/slot configuration etc.

## Details and next steps

- Complete demonstration of 2-layer slot die coating deposition
- Complete demonstration of 1-3 layer slide-die coating deposition
- Document workflows for wider usage
- Document validation against coating trials conducted at ORNL and NREL



# Future Outlook/Plans

- NASCENT ERC in critical 7<sup>th</sup> year of 10.
- Growing interest from thin-film coating and consumer products industries in a research group focused on development and application of high-end simulation tools (*SNL collaborations are essential here* and part of the attraction)
- Grow a modeling and simulation *community of practice* at the AML and joint with several departments (at all scales, from sub-molecular to continuum to system)
- New partners in UMN (Derby group), EERE AMO computational mechanics

National Laboratory Professor position mutually beneficial to UNM and Sandia: Allows for career development of key staff, widens conduit of technology exchange between two neighboring research institutions, promotes collaborations on large grants and proposals.